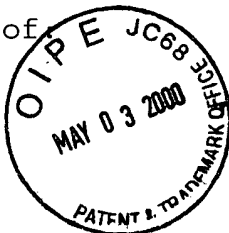


#15/Amendment  
5-9-00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of )  
NISHIMOTO et al )  
Serial No.: 08/897,839 )  
Filed: July 21, 1997 )  
For: STRESS-ADJUSTED INSULATING )  
FILM FORMING METHOD, )  
SEMICONDUCTOR DEVICE AND )  
METHOD OF MANUFACTURING THE )  
SAME )



Group Art Unit: 2814

Examiner: K. Eaton

AMENDMENT IN RESPONSE TO OFFICE ACTION OF FEBRUARY 3, 2000

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

Responsive to the office action of February 3, 2000, please  
amend the captioned application as follows:

IN THE SPECIFICATION:

- N-E Page 7, line 7, change "dyne/cm" to read --dyne/cm<sup>2</sup>--.
- N-E Page 12, line 12, change "dyne/cm" to read --dyne/cm<sup>2</sup>--.
- N-E Page 13, line 12, change "dyne/cm" to read --dyne/cm<sup>2</sup>--.
- N-E Page 20, line 21, change "dyne/cm" to read --dyne/cm<sup>2</sup>--.
- N-E Page 21, line 19, change "dyne/cm" to read --dyne/cm<sup>2</sup>--; and  
line 21, change "dyne/cm" to read --dyne/cm<sup>2</sup>--.
- N-E Page 22, line 16, change "dyne/cm" to read --dyne/cm<sup>2</sup>--.
- N-E Page 23, line 1, change "dyne/cm" to read --dyne/cm<sup>2</sup>--; and  
line 3, change "dyne/cm" to read --dyne/cm<sup>2</sup>--.